



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shuichi YABU

Application No.: 09/811,447

Filed: March 20, 2001

For: EXPOSURE APPARATUS, GAS REPLACING METHOD,
AND METHOD OF MANUFACTURING A
SEMICONDUCTOR DEVICE

Examiner: A. Mathews

Group Art Unit: 2851

December 12, 2002

Commissioner for Patents
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

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☐ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	51	MINUS	55	= 0	x \$9 \$18	\$ 0.00
INDEP. CLAIMS	16	MINUS	4	= 12	x \$42 \$84	\$1,008.00
Fee for Multiple Dependent claims \$140/\$280						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$1,008.00

☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.

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A check in the amount of \$1,008.00 is enclosed including the additional claims fees.



Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.



Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.



A check in the amount of \$_____ to cover the fee for a _____ month extension is enclosed.




A check in the amount of \$____ to cover the Information Disclosure Statement fee is enclosed.



Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicant
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO

30 Rockefeller Plaza

New York, New York 10112-3801

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Washington, D.C. 20231

#4/a
12/17/02
gpr

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AMENDMENT

Sir:

In response to the Official Action dated September 12, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please amend the specification as follows:

Please substitute the paragraph beginning at page 2, line 5, and ending on page 3, line 3, with the following. A marked-up copy of this paragraph, showing the changes made thereto, is attached in Appendix A.

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